



AUG 13 2004

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Attorney Docket No.: 60919 (70551)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: Tetsuya INUI, et al.

U.S.S.N.: 10/789,085 Group No.: 2872

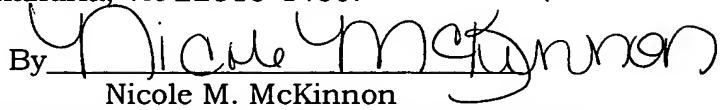
Filed: February 27, 2004 Examiner: Not Yet Assigned

For: CRYSTAL GROWTH APPARATUS AND CRYSTAL GROWTH  
METHOD FOR SEMICONDUCTOR THIN FILM

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CERTIFICATE OF EXPRESS MAILING (Label No.: EV 438977383 US)

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By   
Nicole M. McKinnon

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Mail Stop AMENDMENT  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

INFORMATION DISCLOSURE STATEMENT/REPLACEMENT 1449

An Information Disclosure Statement was filed on February 24, 2004 in the above-referenced U.S. patent application. Applicants subsequently noticed that one of the patents listed on the PTO-1449 was misidentified. As such, submitted herewith is a replacement 1449 in which all of the submitted references are correctly identified.

Please note the correct references were previously submitted with the Information Disclosure Statement filed on February 24, 2004, and are not being resubmitted.

Applicant believes that no fees are due in this matter. However, if for any reason a fee is required, a fee paid is inadequate or credit is owed for any excess fee paid, the Commissioner is hereby authorized and requested to charge Deposit Account No. **04-1105**.

Date: August 11, 2004  
Customer No.: 21874

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## REPLACEMENT 1449 FORM

<b>FORM PTO-1449</b>		<b>DOCKET NO.:</b> 60919 (70551)	<b>SERIAL NO.:</b> 10/789,085
<b>INFORMATION DISCLOSURE STATEMENT</b>		<b>APPLICANT(S):</b> Tetsuya INUI, et al.	
		<b>FILING DATE:</b> February 27, 2004	<b>GROUP NO.:</b> Not Yet Assigned

### UNITED STATES PATENT DOCUMENTS

EXAM. INITIALS		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE

### FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES/NO
	BA	11-307450	11/05/99	JAPAN	H01L	21/20	ABSTRACT
	BB	58-201326	11/24/83	JAPAN	H01L	21/26	ABSTRACT
	BC	2000-505241	04/25/00	JAPAN	H01L	21/20	NO

### OTHER DOCUMENTS (INCLUDING AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.)

CA	Akito Hara, et al., "Nucleus Formation Site of Silicon on Glass and Solidification Direction Control – Aiming to Form Monocrystalline Silicon Si-TFT" Textbook of the 112 <sup>th</sup> workshop of Division of Materials Science and Crystal Technology of the Japan Society of Applied Physics, Division of Materials Science and Crystal Technology of the Japan Society of Applied Physics, pp. 19-25 (2000).						

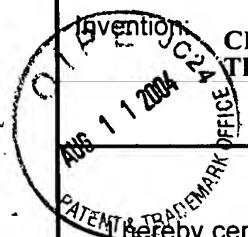
EXAMINER:	DATE:
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**CERTIFICATE OF MAILING BY "EXPRESS MAIL" (37 CFR 1.10)**

Applicant(s): Tetsuya INUI, et al.

Docket No.

60919 (70551)

Serial No.  
10/789,085Filing Date  
February 27, 2004Examiner  
Not Yet AssignedGroup Art Unit  
2872

CRYSTAL GROWTH APPARATUS AND CRYSTAL GROWTH METHOD FOR SEMICONDUCTOR THIN FILM

I hereby certify that the following correspondence:

**Information Disclosure Statement/Replacement 1449 (along with related documents)**

(Identify type of correspondence)

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August 11, 2004

(Date)

**Nicole M. McKinnon**

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